

Notice of References Cited	Application/Control No. 10/638,392		Applicant(s)/Patent Under Reexamination LIN, KAI-CHI	
	Examiner McDieunel Marc		Art Unit 3661	Page 1 of 1

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	B	US-6,817,822 B2	11-2004	Tokunaga, Kenji	414/217
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.